

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Venkat Selvamanickam, et al.
Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)
PROCESS AND APPARATUS TO PRODUCE MULTI-LAYER HIGH-
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPE
App. No.: 10/602,468 Filed: June 23, 2003
Examiner: Aaron Austin Group Art Unit: 1775
Customer No.: 34456 Confirmation No.: 2661
Atty. Dkt. No.: 1014-SP156-US

Mail Stop AMENDMENT
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

REPLY TO OFFICE ACTION

Dear Commissioner:

In response to the Office Action mailed February 10, 2011, please amend the above-identified application as follows:

Claim Amendments begin on page 2.

Remarks begin on page 5.